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PATENT *gusler*

Attorney Docket No. SEL 191

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:)
Koichiro Tanaka, et al.)
Serial No.: 09/610,637)
Filed: July 5, 2000)
Examiner: David S. Blum)
Group Art Unit: 2813)
Title: LASER IRRADIATION APPARATUS,)
LASER IRRADIATION METHOD,)
SEMICONDUCTOR DEVICE AND)
METHOD OF MANUFACTURING A)
SEMICONDUCTOR DEVICE)

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Commissioner for Patents
Washington, D.C. 20231 on:

DATE: April 17, 2003

NAME Christine A. Barglik
(TYPED OR PRINTED)

SIGNATURE Christine A. Barglik

Honorable Commissioner for Patents
Washington, D.C. 20231

RESPONSE TO RESTRICTION REQUIREMENT AND AMENDMENT

Sir/Madam:

In response to the Office Action mailed February 20, 2003, please amend the above-identified patent application as follows.

IN THE CLAIMS:

Please cancel claim 1-60 without prejudice.

Please add the following new claims 67-85.

67. A method of manufacturing a semiconductor device in which a laser beam is simultaneously irradiated from a front surface and a back surface of a substrate,

wherein a shape of a first laser beam irradiated from said front surface and of an irradiation region of a second laser beam

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